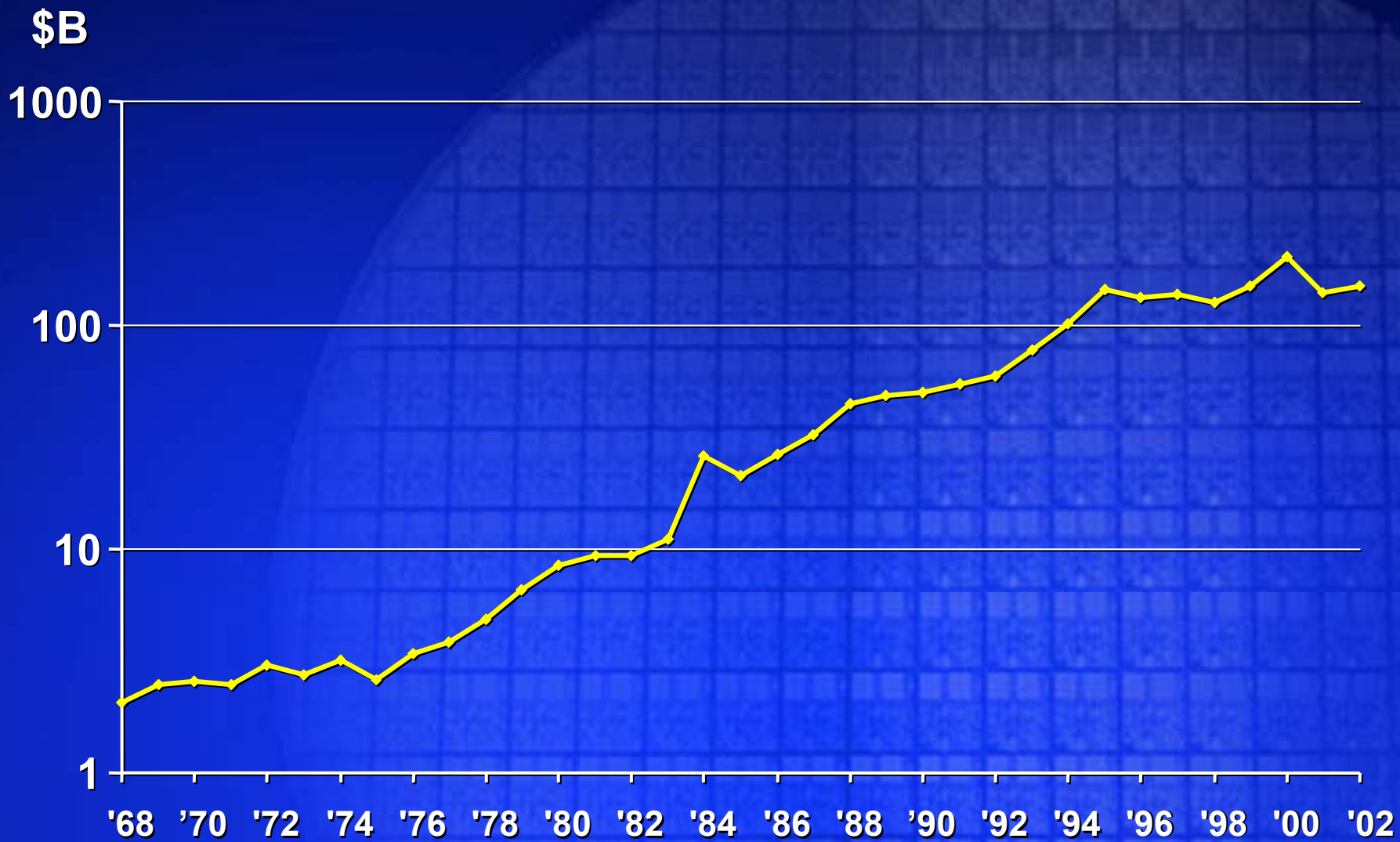


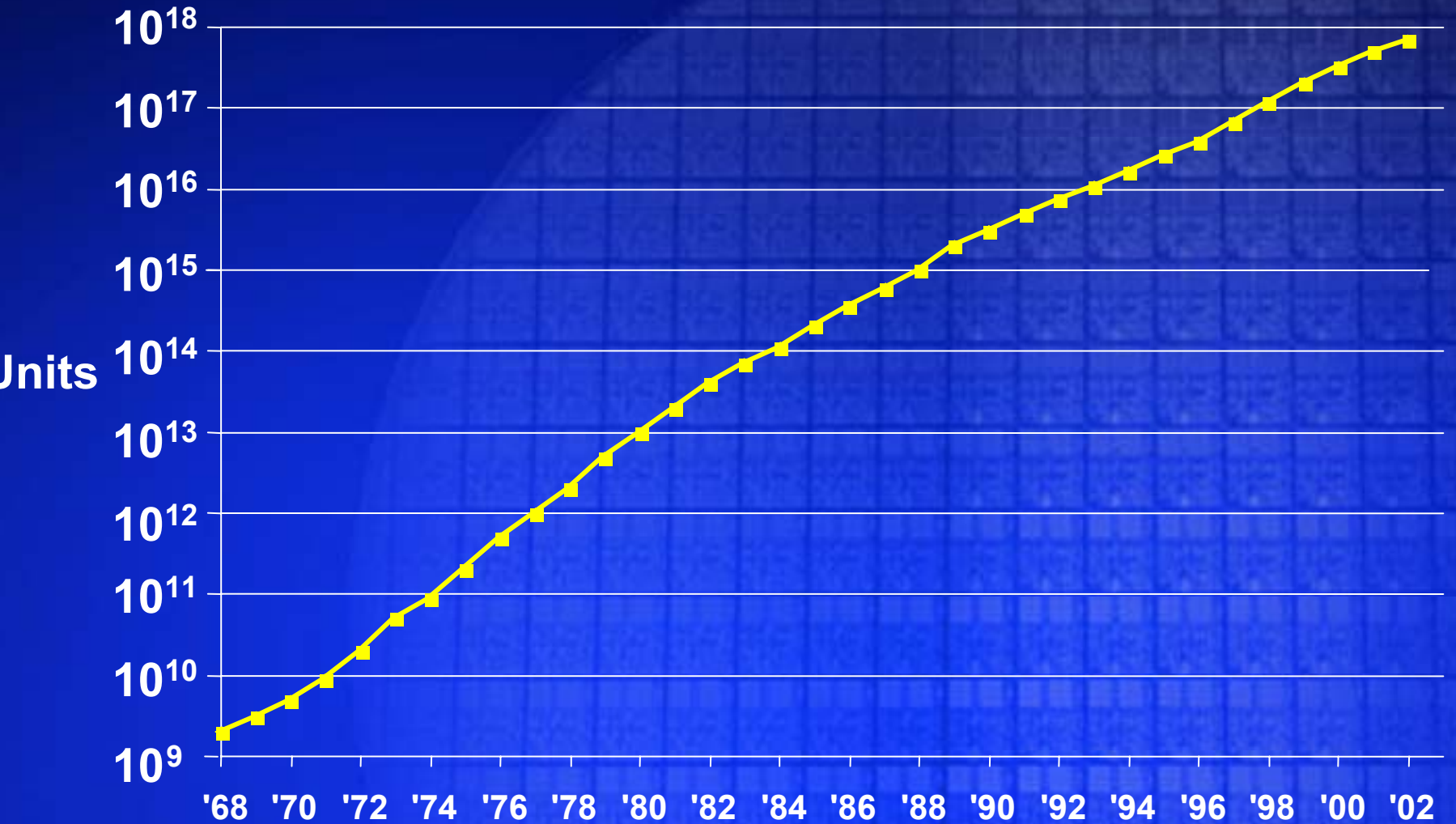
NO EXPONENTIAL IS FOREVER ...

Gordon E. Moore

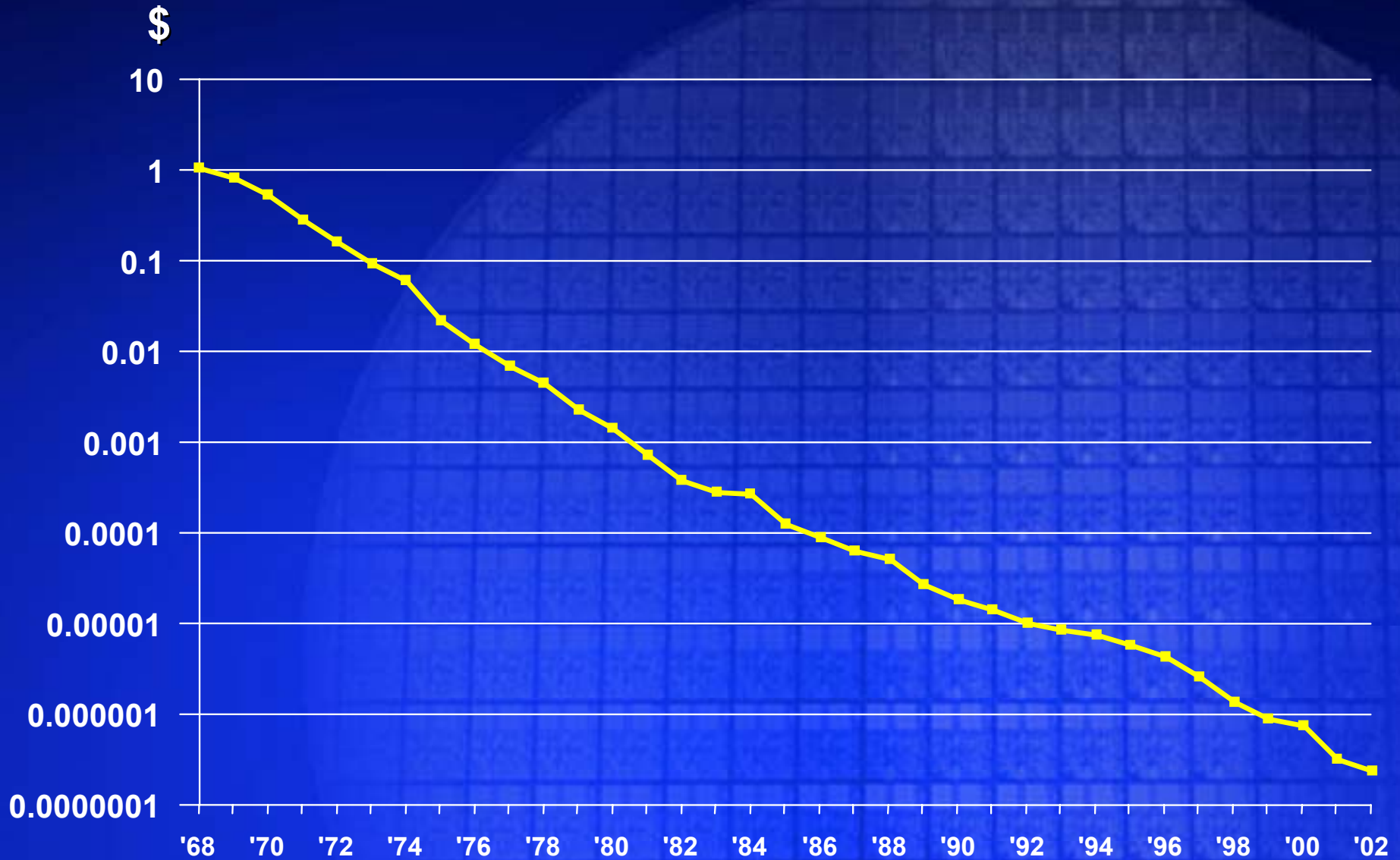
Worldwide Semiconductor Revenues



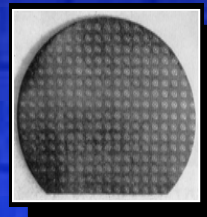
Transistors Shipped Per Year



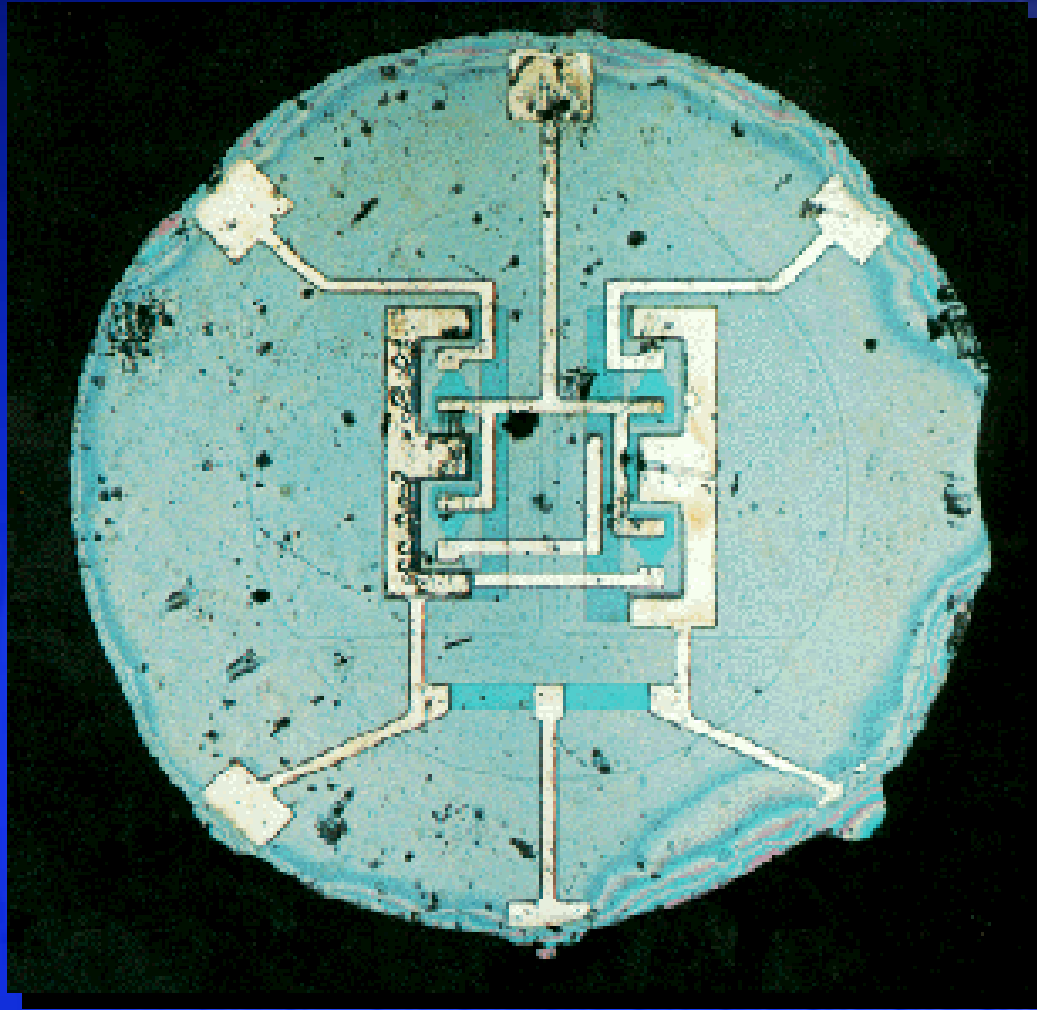
Average Transistor Price By Year



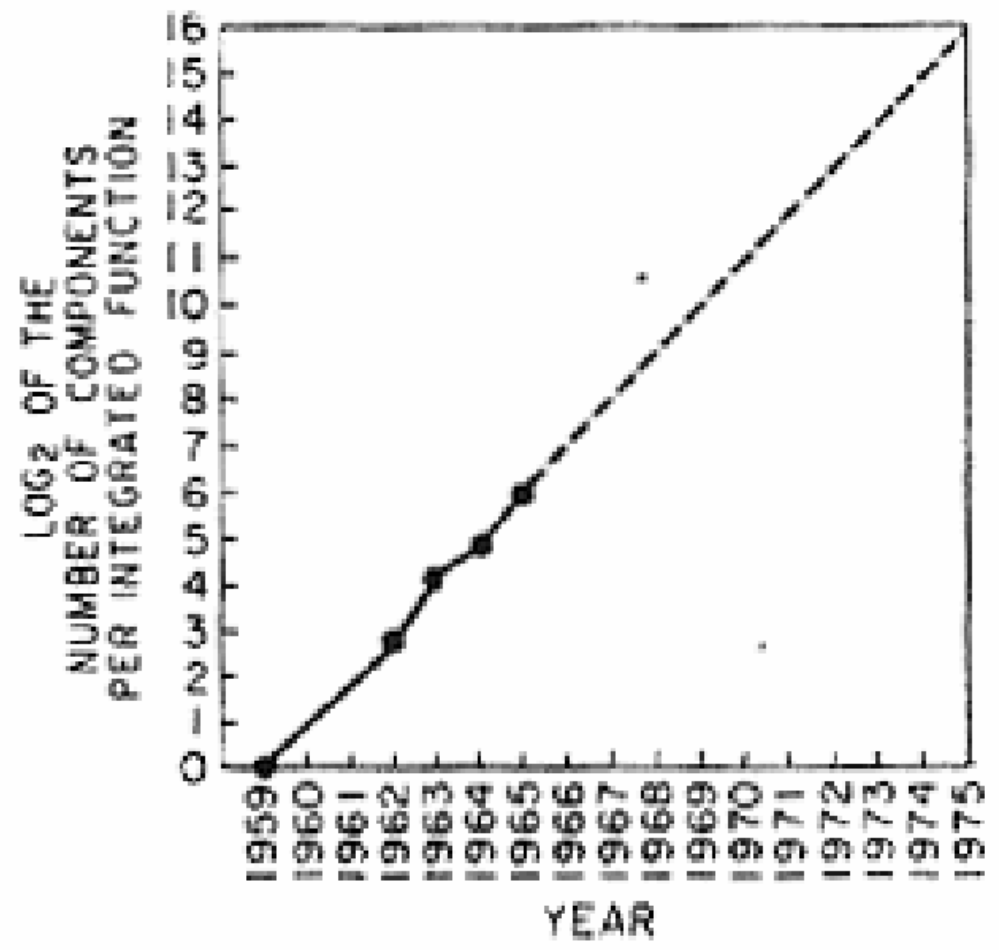
1" Wafer Of Planar Transistors, ~1959



The First Planar Integrated Circuit, 1961



1965 Transistor Projection



Integrated Circuit Complexity

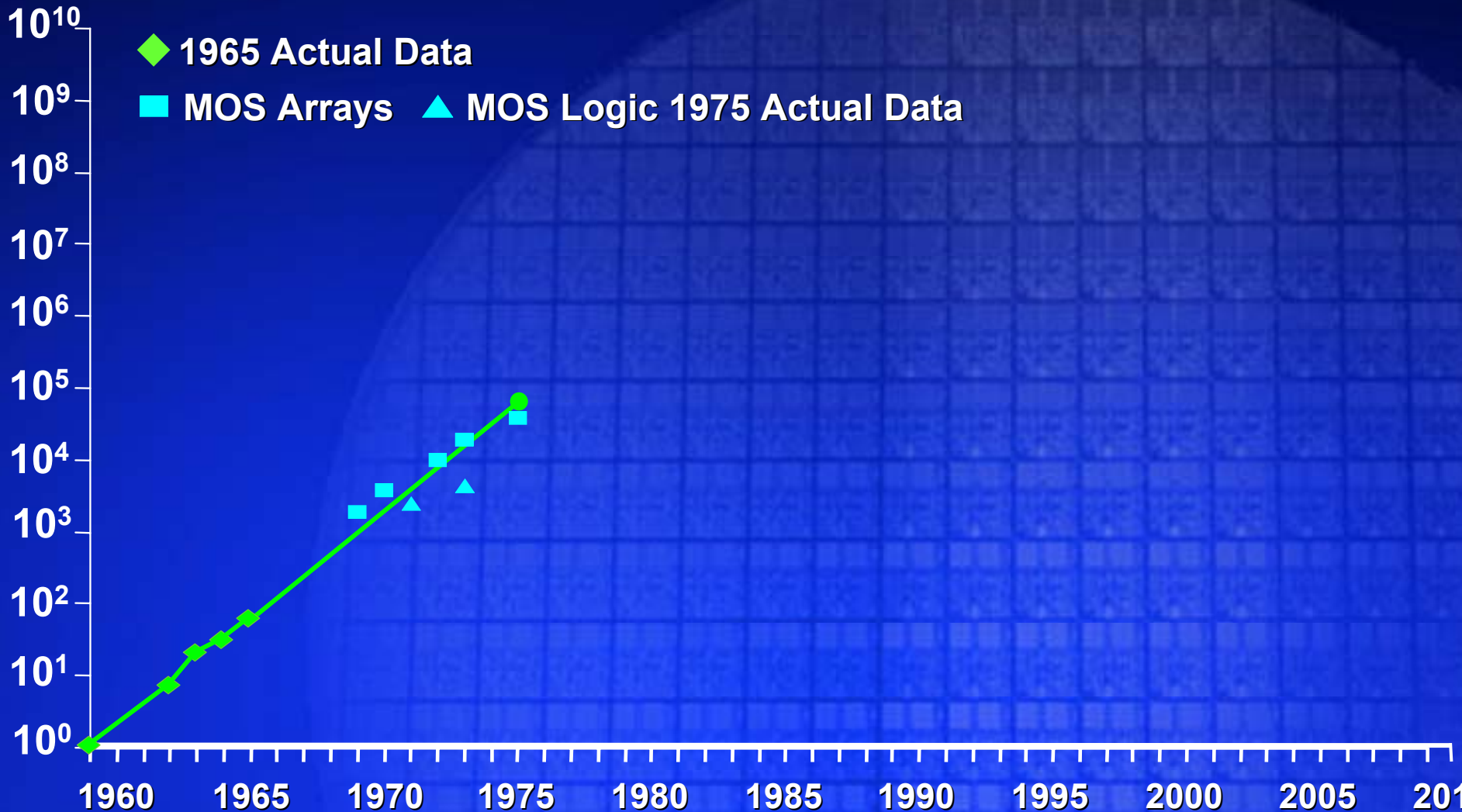
Transistors
Per Die

◆ 1965 Actual Data

■ MOS Arrays

▲ MOS Logic

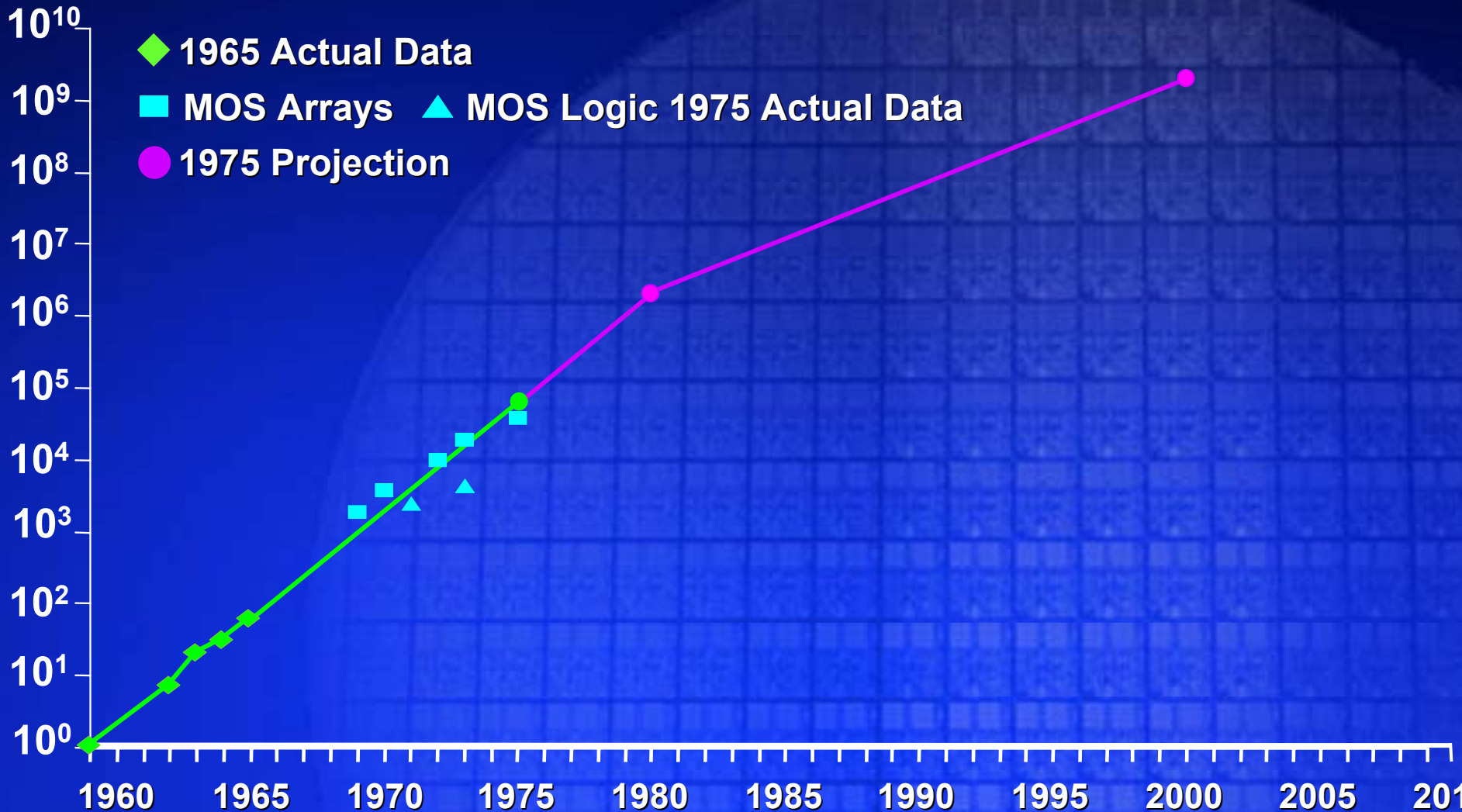
● 1975 Actual Data



Integrated Circuit Complexity

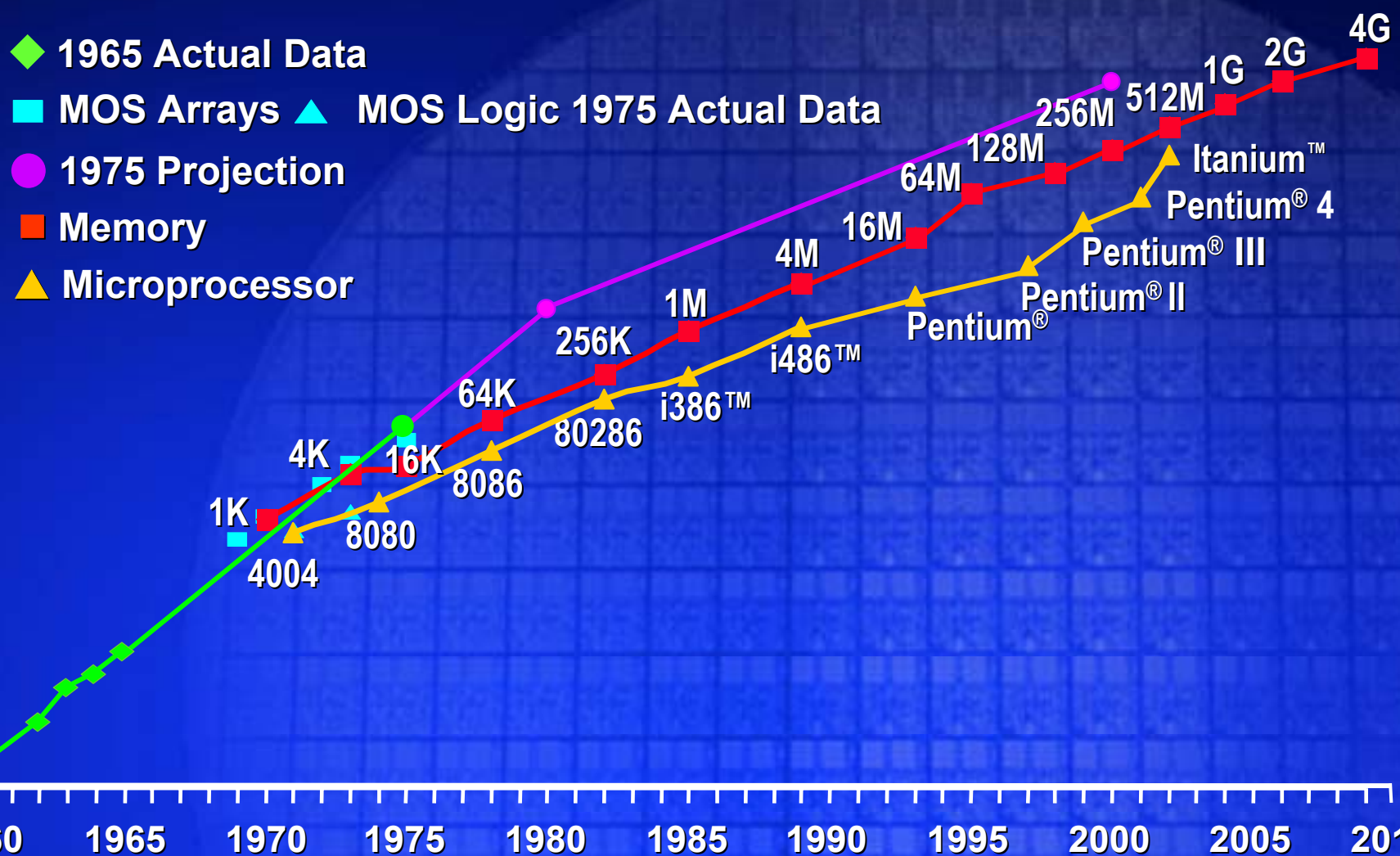
Transistors
Per Die

- ◆ 1965 Actual Data
- MOS Arrays ▲ MOS Logic 1975 Actual Data
- 1975 Projection

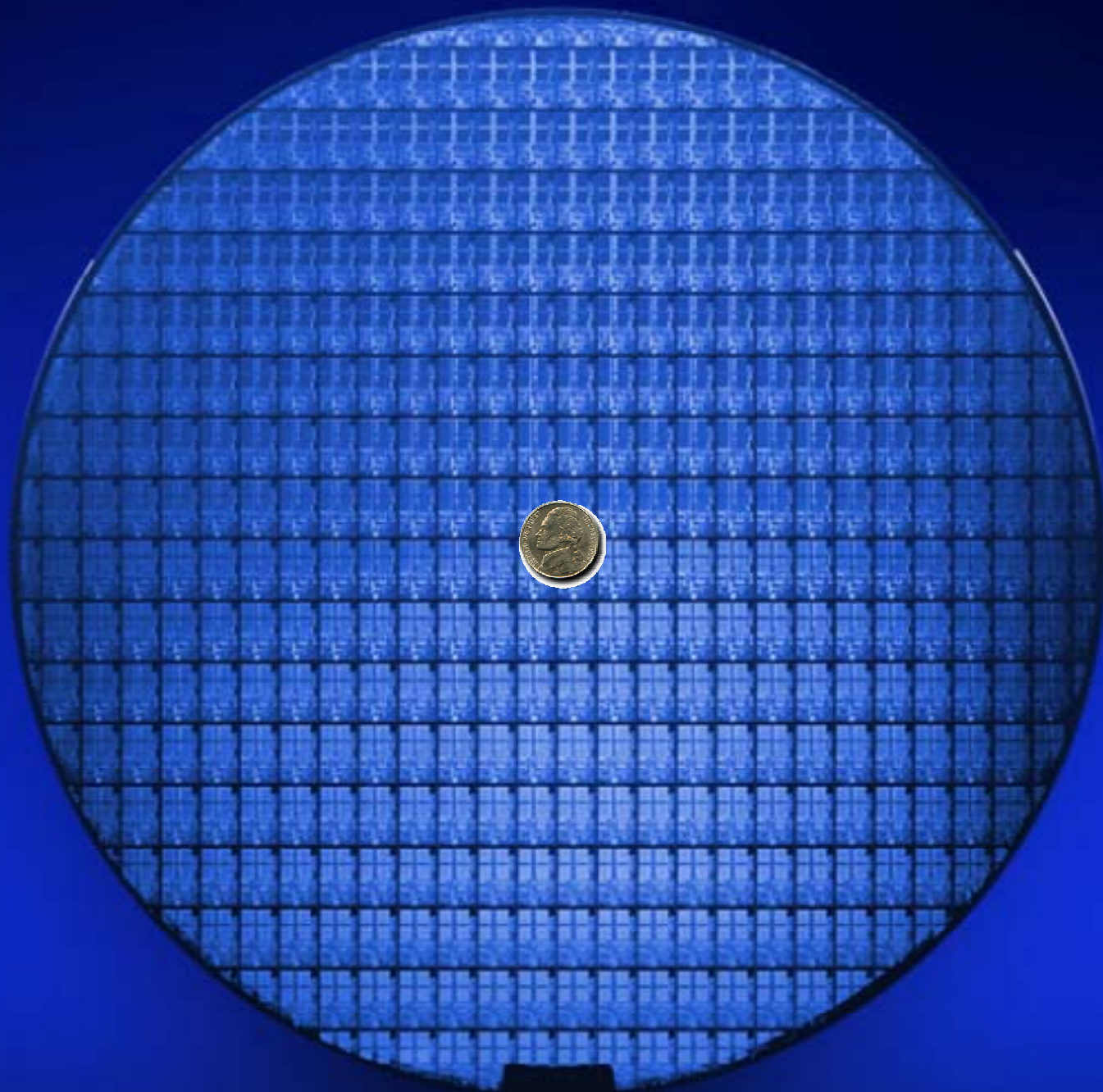


Integrated Circuit Complexity

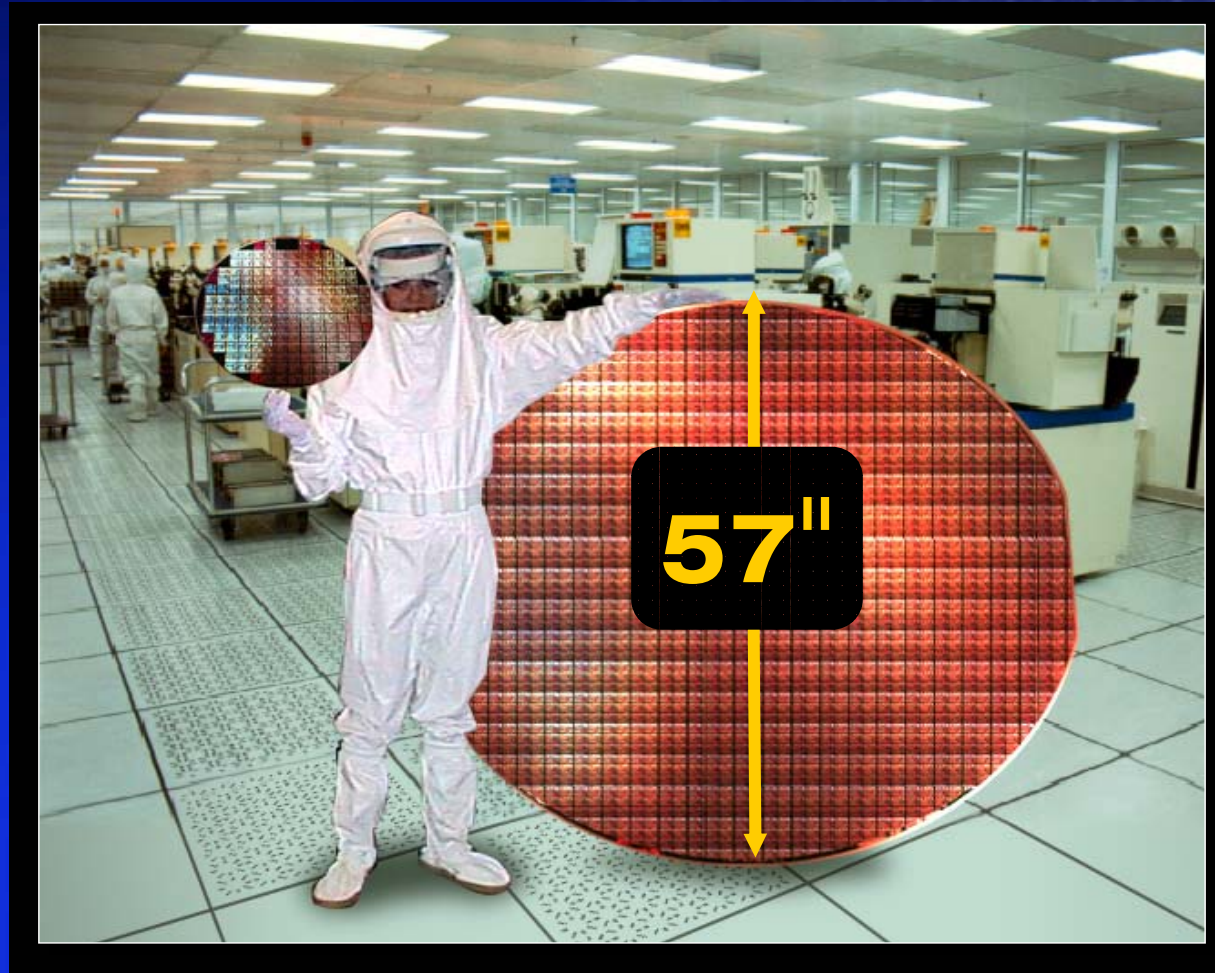
Transistors
Per Die



300mm Wafer

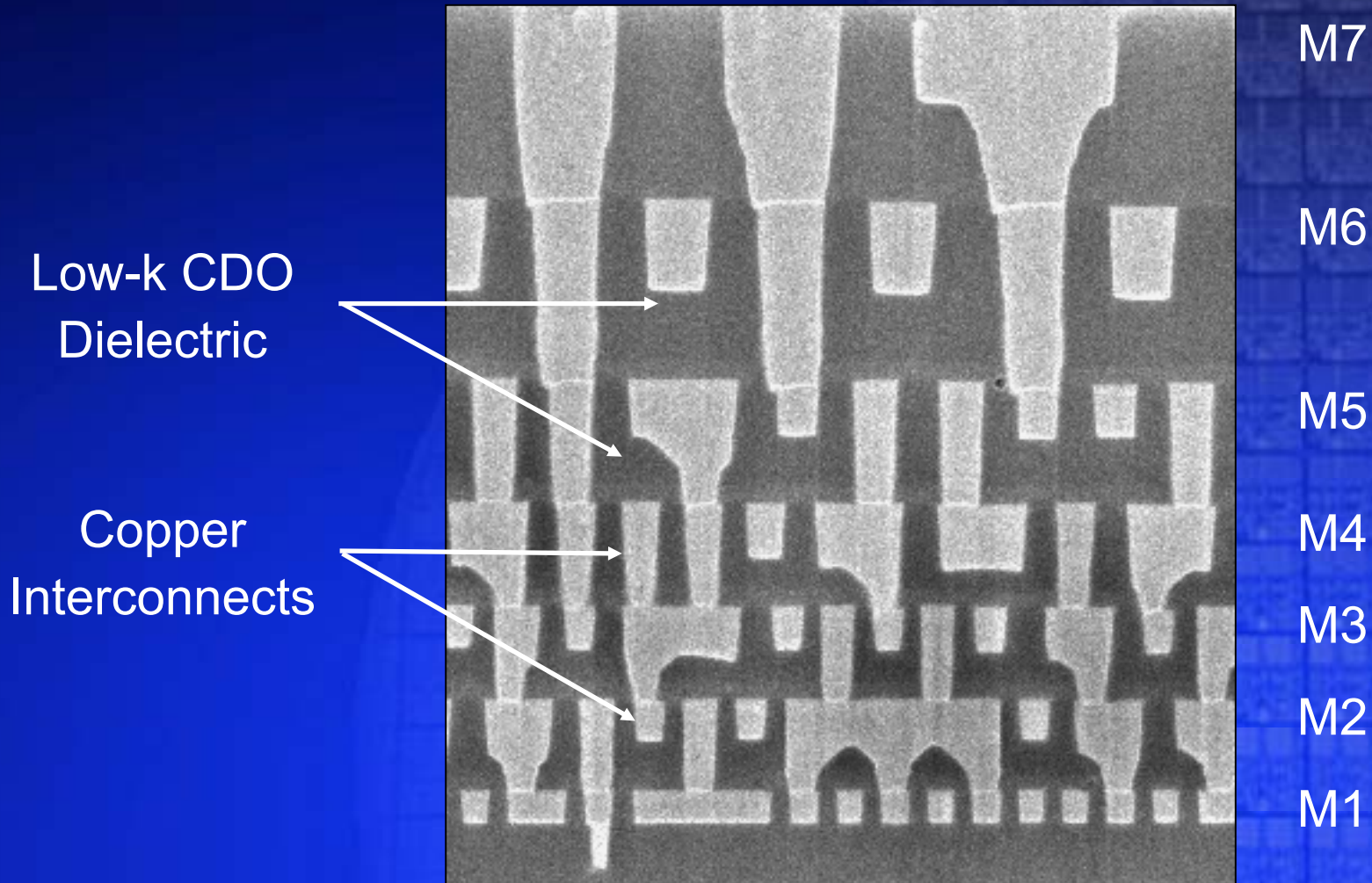


Projected 2000 Wafer, circa 1975



Moore was not always accurate

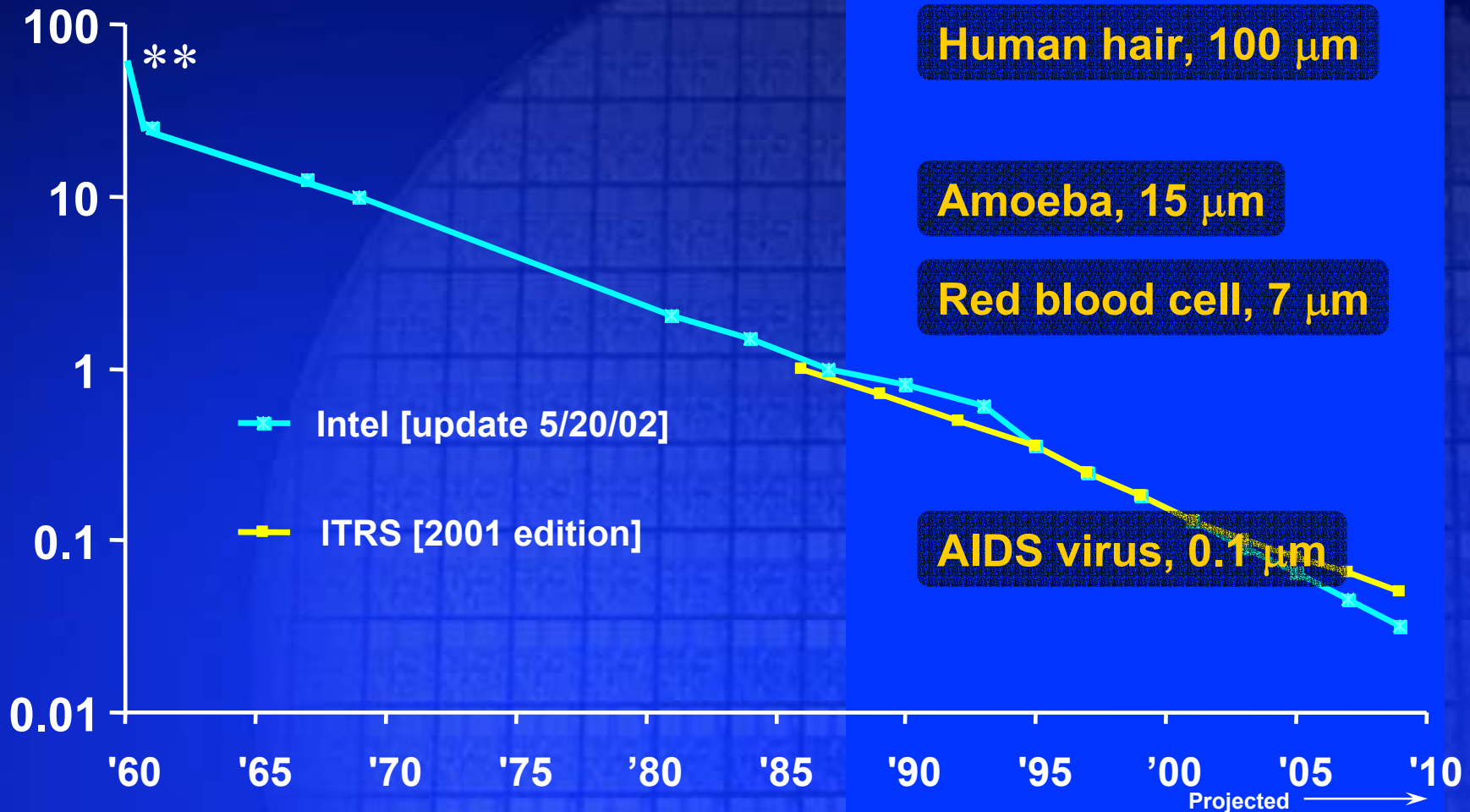
90 nm Generation Interconnects



Combination of copper + low-k dielectric now meeting performance and manufacturing goals

Minimum Feature Size

Feature Size
(microns)



** Planar Transistor; remaining data points are ICs.
Source: Intel, post '96 trend data provided by SIA
International Technology Roadmap for Semiconductors (ITRS)

1 μm^2 SRAM Cell

P501 Contact
1978

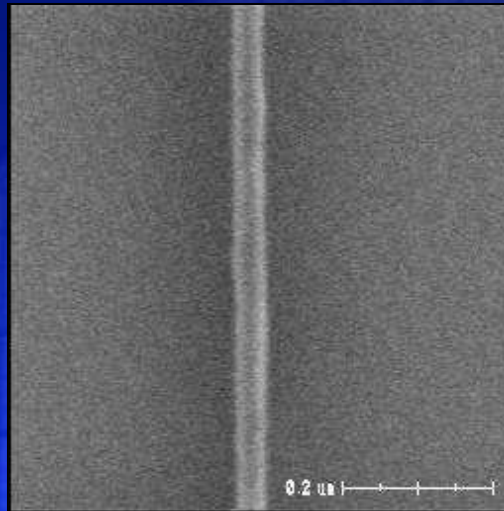
P1262 SRAM Cell
2002



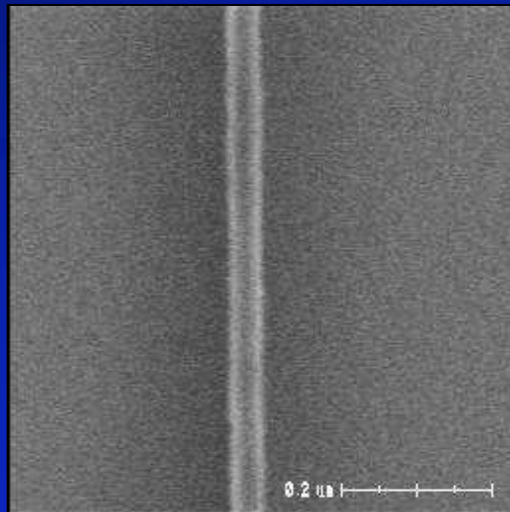
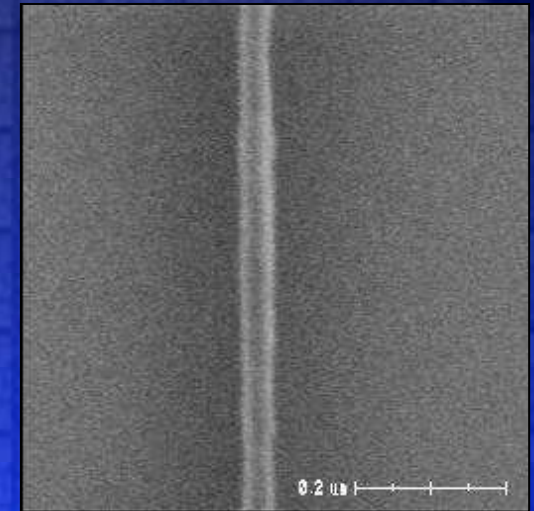
1 μm

50nm Resist Lines With 193nm Light

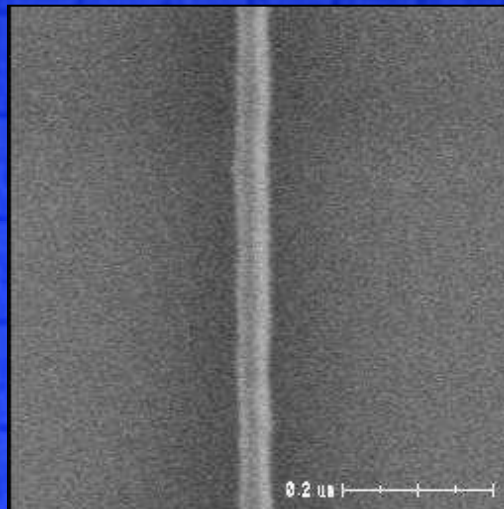
-0.2um focus



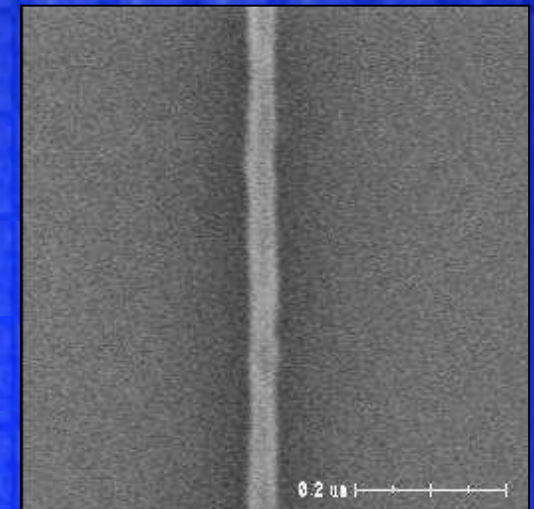
-0.3um focus



“best focus”



+0.2um focus



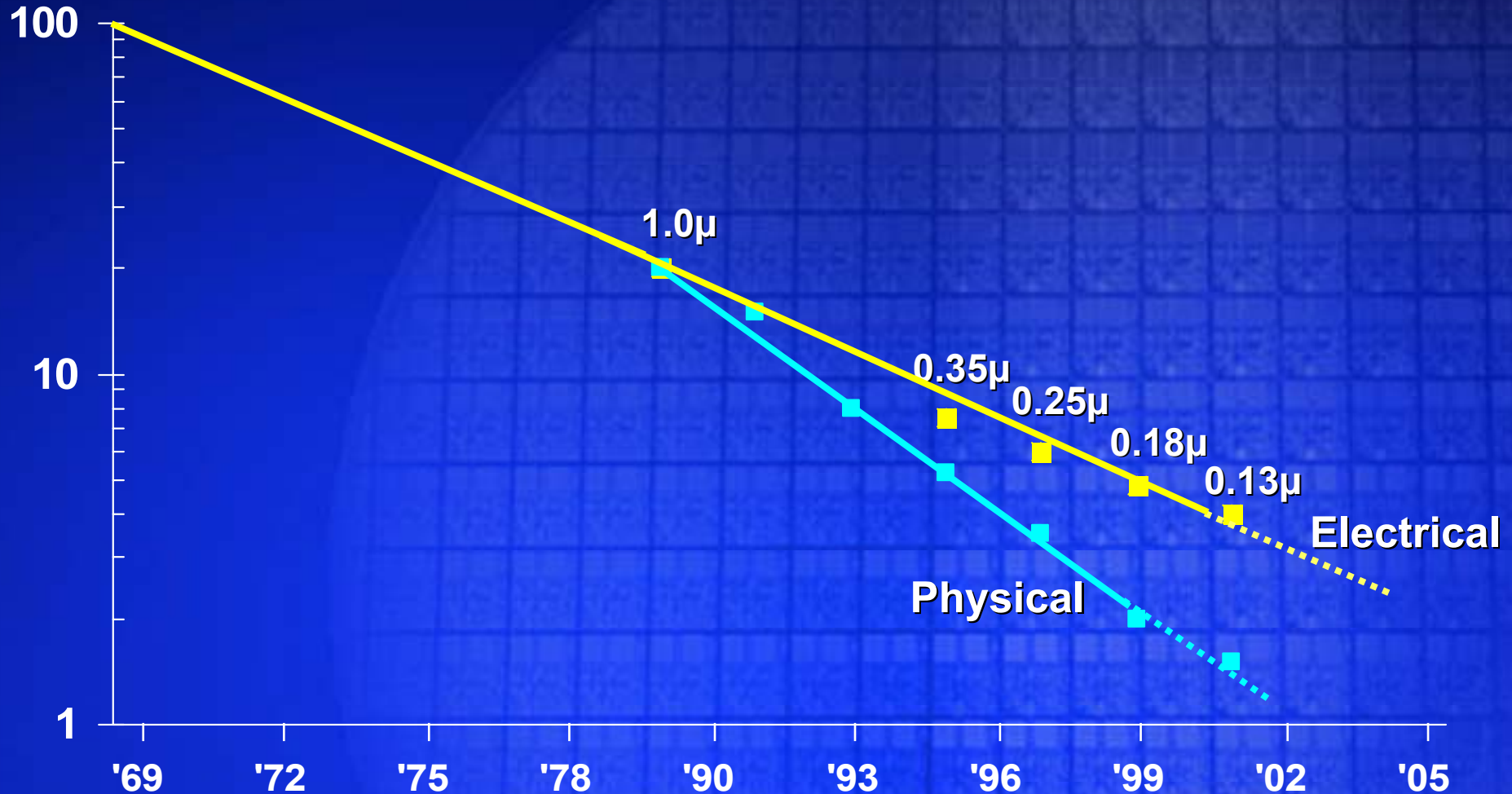
+0.3um focus

193nm Step and Scan Production Tool

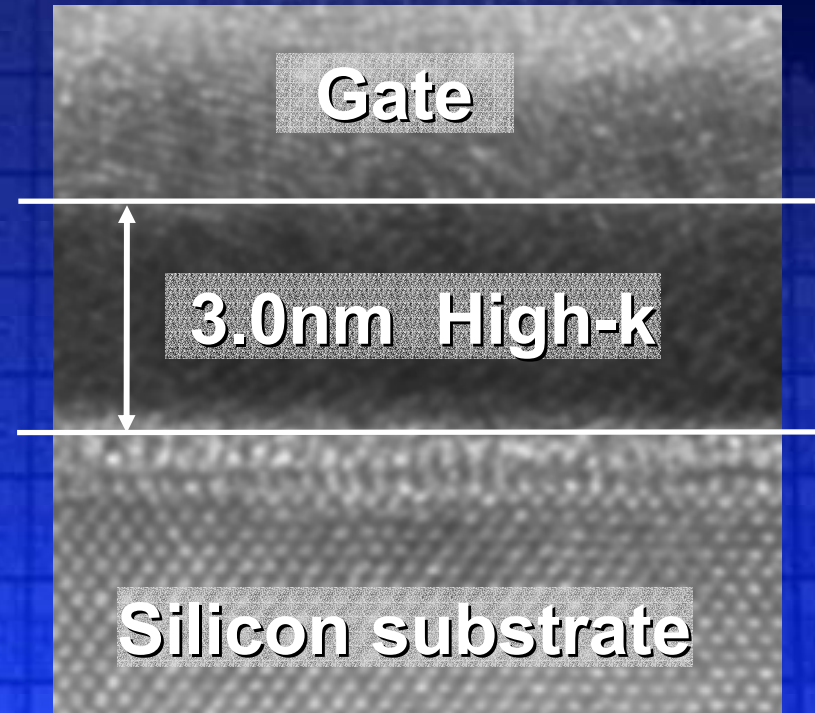
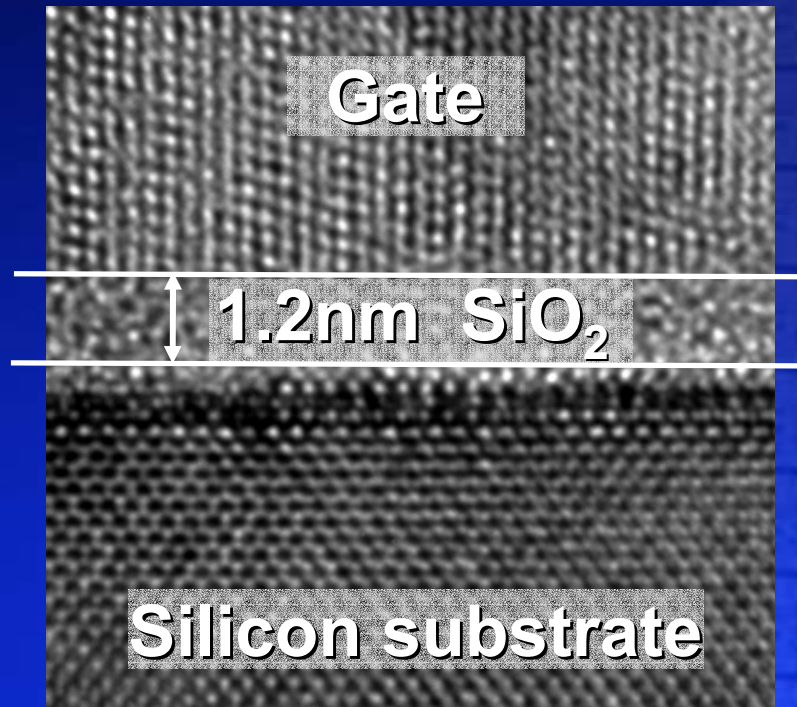


Minimum Insulator Thickness vs Time

Oxide Thickness
(Nanometers)



High K for Gate Dielectrics

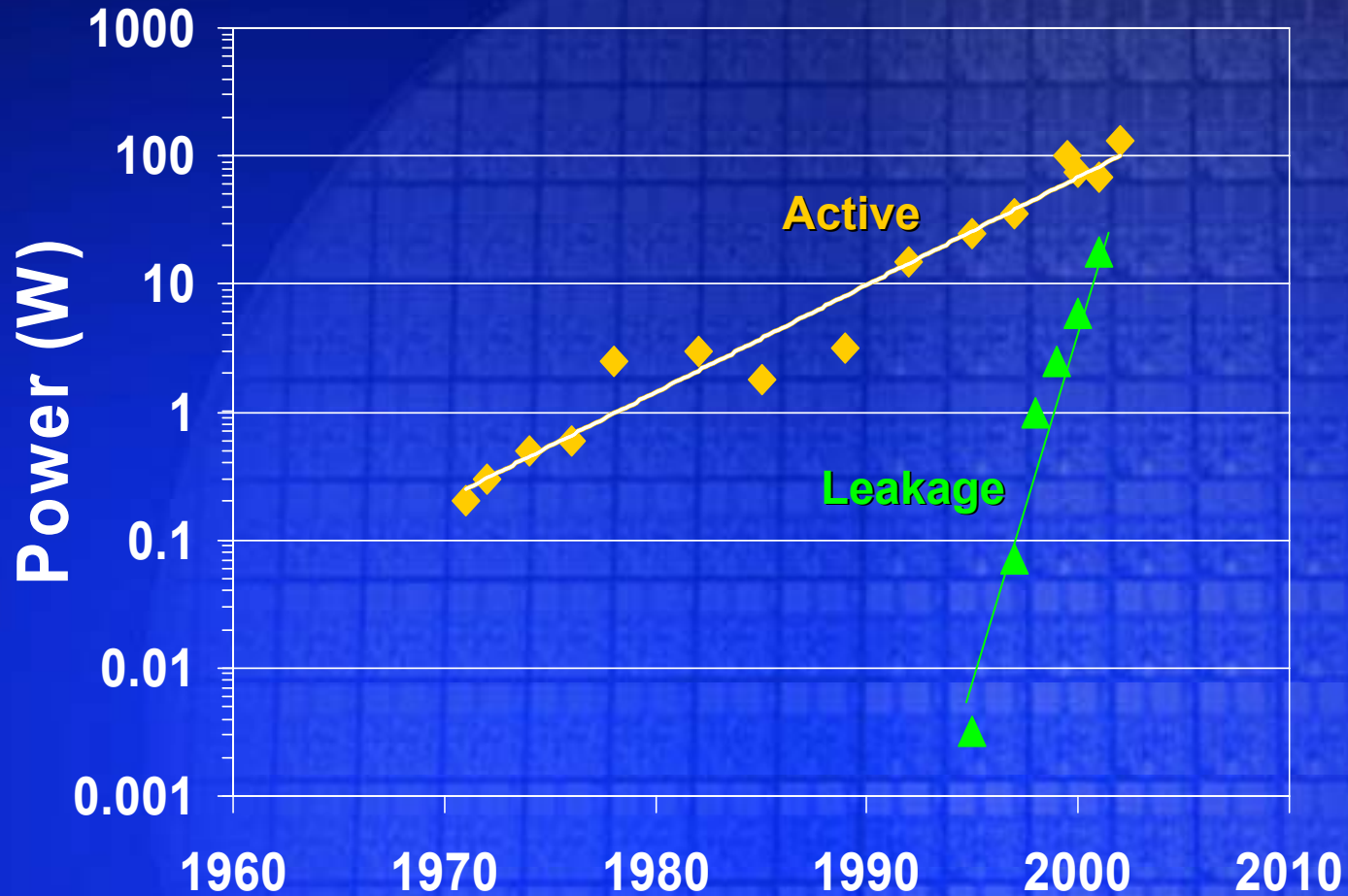


| | 90nm process | Experimental high-k |
|-------------|--------------|---------------------|
| Capacitance | 1X | 1.6X |
| Leakage | 1X | < 0.01X |

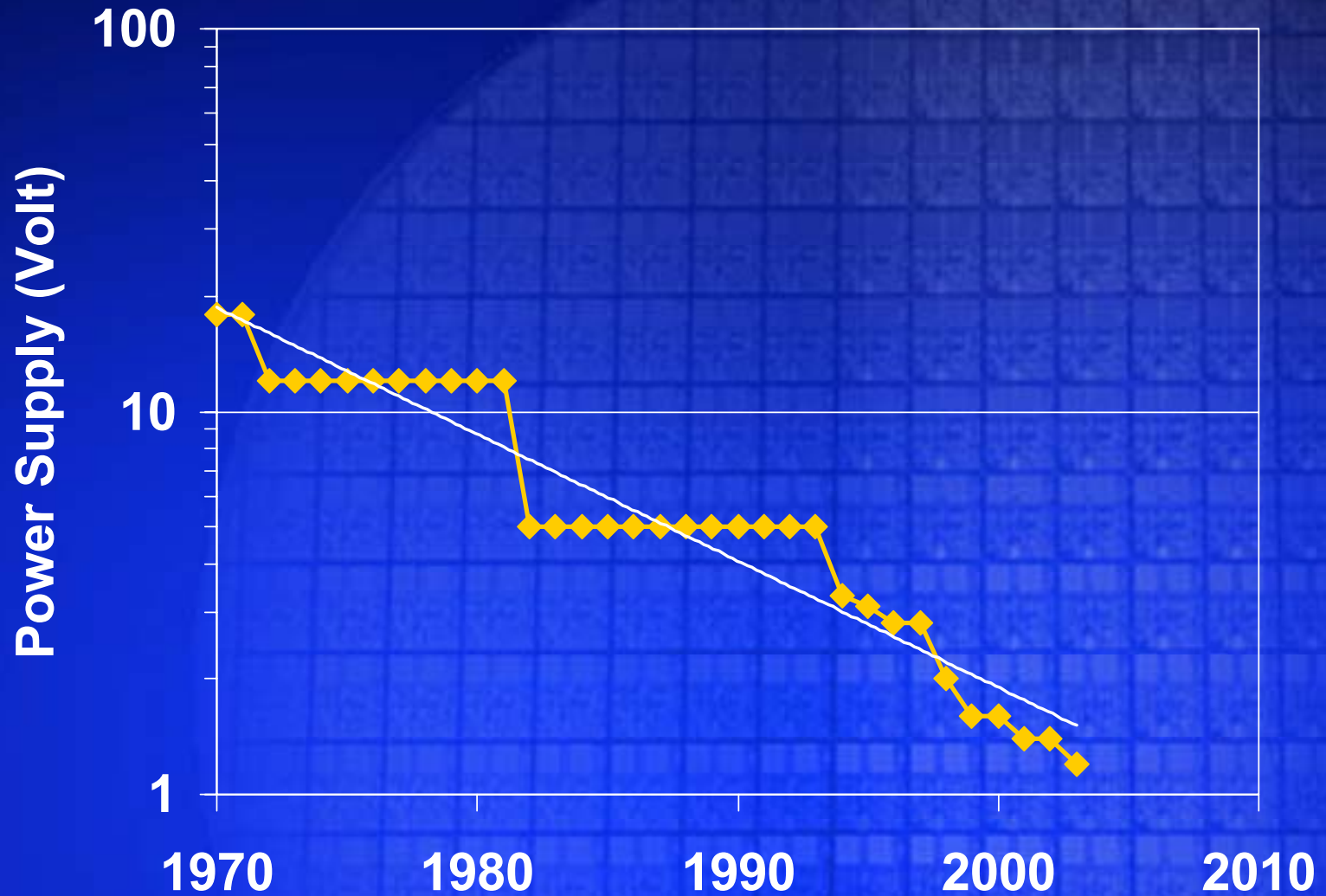
Processor Performance (MIPS)



Processor Power (Watts) - Active & Leakage



Processor Supply Voltage

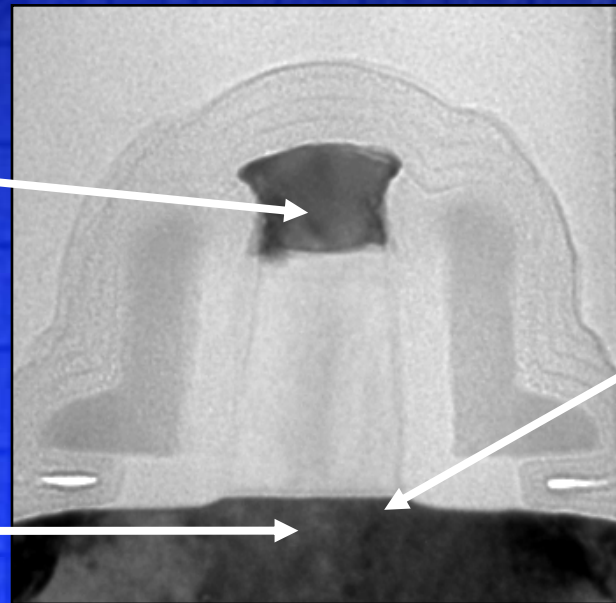


New Materials and Device Structures Extending Transistor Scaling

*Changes
Made*

Gate
Silicide
Added

Channel
Strained
Silicon



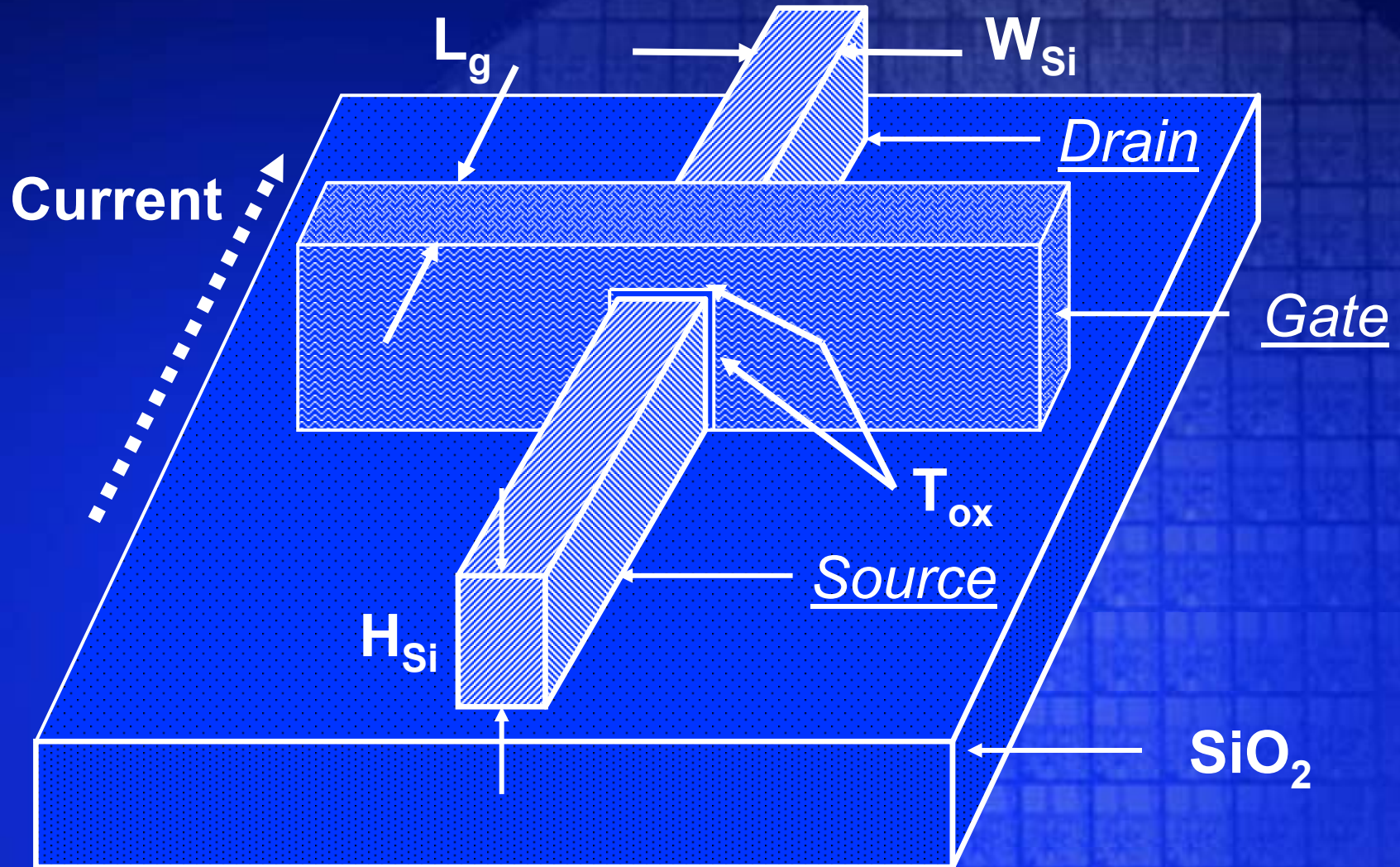
*Future
Options*

High-k
Gate
Dielectric

New
Transistor
Structure

Transistor

Tri-Gate Transistor Structure



Technology Generations to Come

Double the Density
Reduce Line Width by 0.7x

130nm → 90nm → 60nm → 45nm → 30nm → ?

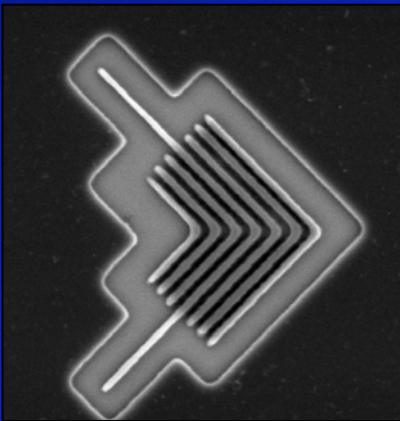
2 or 3 years between generations

∴

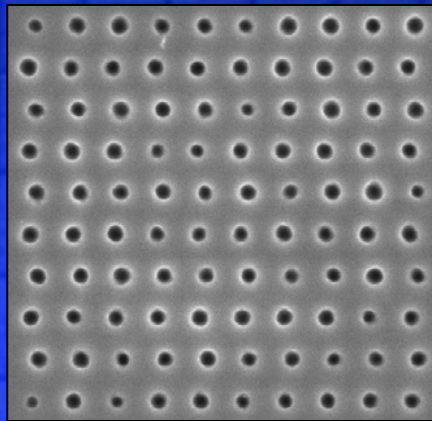
~10 ± 2 Years

EUV Printed and Etched Lines

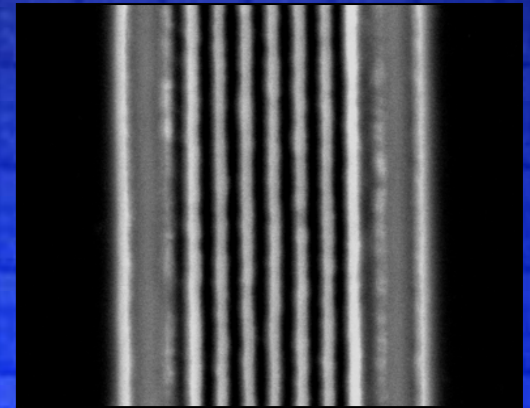
100 nm, $k_1 = 0.75$



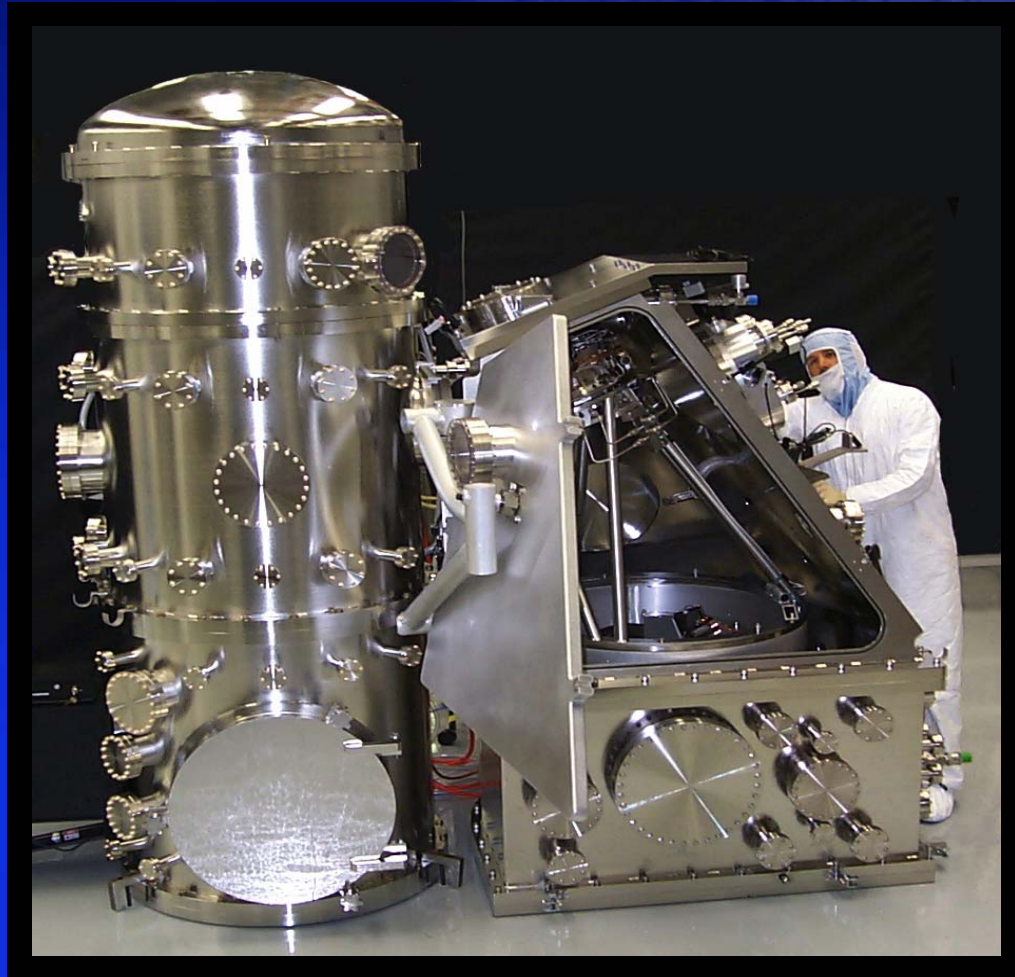
80 nm, $k_1 = 0.60$



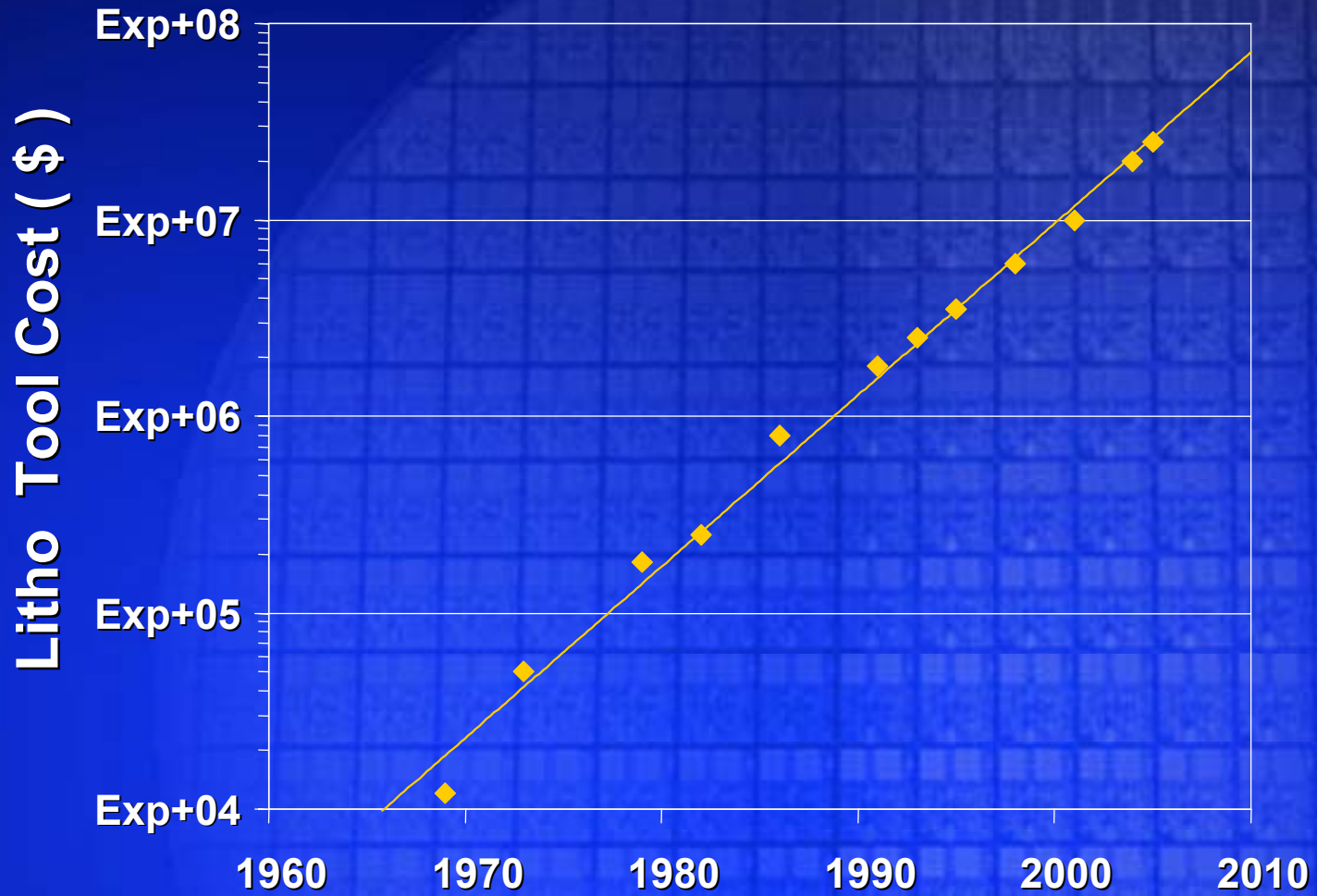
50 nm dense, $k_1 = 0.37$



Extreme Ultraviolet (EUV) Lithography



Lithography Tool Cost (\$)



NO EXPONENTIAL IS FOREVER . . .

BUT

WE CAN DELAY “FOREVER”